

# **HALO RP**Reduced-Pressure Trace Level Analyzer

**GASES & CHEMICALS** 

CEMS

ENERGY

SEMI & HB LED

**ATMOSPHERIC** 

LAB & LIFE SCIENCE

# Designed for trace level analysis at reduced pressure conditions and available for the detection of H<sub>2</sub>O or HF, the HALO RP offers:

- Low parts per billion (ppb) detection capability in inert, acid, and hydride background gases
- Absolute measurement (freedom from calibration gases)
- Wide dynamic range—over four orders of magnitude
- Low cost of ownership and operational simplicity
- Clean technology—no external calibration gases required
- CRDS technology, designated by SEMI-F112 06-13 Standard

#### **Protect Your Product with the HALO RP**

It's one thing to be monitoring and have high confidence in your high purity bulk and speciality gases at the post-purifier stage but a lot can change as that same gas then travels through the various fab distribution systems and arrives at the equipment or process chamber. Unless you are monitoring close to the substrate or in the process chamber exhaust, there is risk that high partial pressures of moisture are present during processing, resulting in defects causing yield loss and reliability issues.

For example, in semiconductor fabrication, moisture or hydrogen fluoride present in low-temperature epitaxy (LTE) can affect the quality and strain of the epi layers. In MOCVD processing with hydride gases,

excess moisture can lead to significant reduction in luminescence and yield loss.

This is where Tiger Optics comes in. Able to operate in a pressure range from 50 Torr to 15 psig, the HALO RP trace level analyzer provides users with the unmatched accuracy, reliability, speed of response and ease of operation that users of Tiger Optics' analyzers have come to expect. The HALO RP is available for two different analytes, H<sub>2</sub>O and HF, to ensure that your product is protected from all harmful molecules.

Monitoring for contaminants close to the substrate or in the process chamber exhaust, significantly reduces the risk of process issues that cause product yield losses.



## **HALO RP**

# Reduced-Pressure Trace Level Analyzer



HxWxD[in (mm)]

8.73 x 8.57 x 26.4 (222 x 218 x 670)

8.73 x 19.0 x 26.4 (222 x 483 x 670)

Performance	
Operating range	See table below
Detection limit (LDL, 3σ/24h)	See table below
Precision ( $1\sigma$ , greater of)	± 1% or 1/3 of LDL
Accuracy (greater of)	± 4% or LDL
Speed of response	< 3 minutes to 95%
Environmental conditions	10°C to 40°C
	30% to 80% RH (non-condensing)
Storage temperature	-10°C to 50°C

Gas Handling System and Conditions*		
Wetted materials	316L stainless steel	
	(corrosive gas version optional)	
	10 Ra surface finish	
Gas connections	1/4" male VCR inlet and outlet	
Leak tested to	1 x 10 <sup>-9</sup> mbar I / sec	
Inlet pressure	50 Torr – 15 psig (0.07 – 2 bara)	
Outlet pressure	<10 Torr (13 mbar)	
Flow rate	0.1 to 1.0 slpm	
Sample gases	N <sub>2</sub> , H <sub>2</sub> , Ar, He, HCl, and others	
Gas temperature	Up to 60°C	

	(corrosive gas version optional)
	10 Ra surface finish
Gas connections	1/4" male VCR inlet and outlet
Leak tested to	1 x 10 <sup>-9</sup> mbar l / sec
Inlet pressure	50 Torr – 15 psig (0.07 – 2 bara)
Outlet pressure	<10 Torr (13 mbar)
Flow rate	0.1 to 1.0 slpm
Sample gases	N <sub>2</sub> , H <sub>2</sub> , Ar, He, HCl, and others
Gas temperature	Up to 60°C

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	30% to 80% RH (non-condensing)	Standard sensor	30 lbs (13.4 kg)
Storage temperature	-10°C to 50°C		
		Electrical	
Gas Handling System and Conditions*		Alarm indicators	2 user programmable
Wetted materials	316L stainless steel		1 system fault
	(corrosive gas version optional)		Form C relays
	10 Ra surface finish	Power requirements	90 – 240 VAC, 50/60 Hz
Gas connections	1/4" male VCR inlet and outlet	Power consumption	40 Watts max.
_eak tested to	1 x 10 <sup>-9</sup> mbar l / sec	Signal output	Isolated 4-20 mA per sensor
nlet pressure	50 Torr – 15 psig (0.07 – 2 bara)	User interfaces	5.7" LCD touchscreen
Outlet pressure	<10 Torr (13 mbar)		10/100 Base-T Ethernet
Flow rate	0.1 to 1.0 slpm		802.11g Wireless (optional)
Sample gases	N <sub>2</sub> , H <sub>2</sub> , Ar, He, HCl, and others		RS-232
Gas temperature	Up to 60°C		Modbus TCP (optional)
/acuum cource required			

**Dimensions** 

Sensor rack

Weight

Standard sensor

(incl. shutoff valves)

(fits up to two sensors)



<sup>\*</sup>Vacuum source required

## **HALO RP**

# Reduced-Pressure Trace Level Analyzer

#### **HALO RP H<sub>2</sub>O — Trace Moisture Analyzer (Standard Model)**

Performance, H <sub>2</sub> O:	Range	LDL (3σ)	Precision (1σ) @ zero
In Nitrogen	0 – 20 ppm	1.5 ppb	0.5 ppb
In Argon	0 – 20 ppm	1.5 ppb	0.5 ppb
In Hydrogen	0 – 20 ppm	1.5 ppb	0.5 ppb
In Helium	0 – 12 ppm	1.0 ppb	0.3 ppb
In HCI <sup>†</sup>	0 – 25 ppm	3 ppb	1.0 ppb
In Phosphine <sup>‡</sup>	0 – 10 ppm	9 ppb	3 ppb

### **HALO RP H<sub>2</sub>O — Trace Moisture Analyzer (Arsine Model)**

Performance, H <sub>2</sub> O:	Range	LDL (3σ)	Precision (1σ) @ zero
In Arsine <sup>‡</sup>	0 – 10 ppm	5 ppb	2 ppb
In Nitrogen	0 – 6 ppm	1.0 ppb	0.3 ppb
In Helium	0 – 3 ppm	1.0 ppb	0.3 ppb

## **HALO RP HF** — Trace Hydrogen Fluoride Analyzer

Performance, HF:	Range	LDL (3σ)	Precision (1σ) @ zero
In Nitrogen	0 – 10 ppm	0.75 ppb	0.25 ppb
In BF <sub>3</sub>	0 – 13 ppm	0.9 ppb	0.3 ppb

<sup>&</sup>lt;sup>†</sup>May require corrosive gas version, please contact us for more information <sup>‡</sup>Low leak rate vacuum pump required

Contact us for additional analytes and matrices.

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